

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2812

Examiner: Stanetta D. Isaac

In Re PATENT APPLICATION of:

Applicant(s): Jun KANAMORI

Serial No.: 10/634,851

Filing Date: August 6, 2003

For: SEMICONDUCTOR DEVICE FABRICATION

METHOD USING OXYGEN ION

**IMPLANTATION** 

Atty. Ref.: MAE 292

May 25, 2006

**AMENDMENT** 

Mail Stop AF

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## Madam:

In response to the Examiner's Action mailed on February 28, 2006, please amend the above-identified application as follows: